SEMICAPS 1100

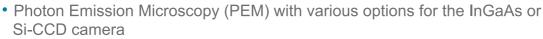
UPRIGHT ANALYTICAL SYSTEM



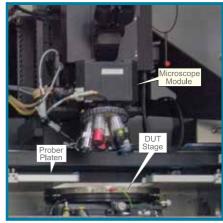
Features

- For backside and frontside analysis of wafers, wafer parts and packaged devices
- Ultra-stable system compatible for probing FIB pads
- Compatible with third-party probe stations, probe cards and manipulators
- High resolution stage with 0.5 µm repeatability
- Aplanatic Refractive Solid Immersion Lens (ARSIL) option, currently probing 3nm nodes
- CAD interface option
- Analysis Methodologies include a combination of:
 - Laser Timing Probe (LTP)
 - Scanning Optical Microscopy (SOM) with best sensitivity for

static analysis: TIVA, OBIRCH dynamic analysis: LADA, SDL



Thermal Microscopy (THM)



300 mm Probe Station

